

*[Handwritten Signature]*

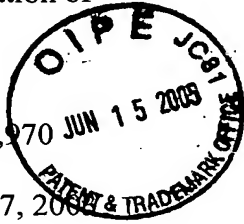
**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re patent application of

Allowed: May 26, 2005

Seiji Nagai et al.

Serial No.: 10/620,970



Group Art Unit: 1765

Filing Date: July 17, 2004

Examiner: Hiteshew, Felisa Carla

For: METHOD FOR PRODUCING SEMICONDUCTOR CRYSTAL

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

Sir:

Under the provisions of 37 CFR §1.97 through §1.99 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following documents cited in the Korean Office Action and listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. Copies of the listed documents are provided herewith for the convenience of the Examiner.

In compliance with the requirements of 37 CFR §1.98(a)(3), as a concise statement of relevance, as it is presently understood by the individual designated in 35 U.S.C. §1.56(c) most knowledgeable about the content of the information, the undersigned attorney of record submits a translation of portions of an official action by a foreign examiner in which the reference was cited. The relevance to the pending U.S. patent application is that the reference was cited in a foreign patent application on the same subject matter. However, no independent analysis of the reference, the accuracy of the statement of the foreign examiner or the claims of the foreign application under the laws of that country or the United States relative to the subject matter claimed in the present application has been made, the present understanding of the contents thereof by the undersigned being based on the translation of the foreign examiner's comments submitted herewith.

This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

06/17/2005 HALI11 00000018 10620970

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10/620,970  
T36-157933M/RS  
NGB.271

I hereby certify that each item of information contained in this Information Disclosure Statement was the first citation of that item by a foreign patent office in a counterpart foreign application, which occurred not more than three months prior to the filing of this statement.

Submitted herewith is the IDS fee of \$180.00.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's Deposit Account No. 50-0481.

Respectfully submitted,



Sean M. McGinn

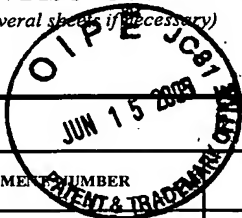
Registration No. 34,386

Date: \_\_\_\_\_

6/15/05  
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# INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)



Docket Number (Optional)  
**T36-157933M/RS**

Application Number  
**10/620,970**

Applicant(s)  
**Seiji Nagai et al.**

Filing Date  
**July 17, 2003**

Group Art Unit  
**1765**

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

## U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

## FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
		2001-217455	08/10/01	JAPAN			ABS	
		2001-313259	11/09/01	JAPAN			ABS	

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Korean Office Action dated March 23, 2005, with Japanese translation and partial English translation.

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.